



**TechnoTeam**  
Bildverarbeitung GmbH



## Far-field measurements with RIGO801 near-field goniophotometers

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## Introduction

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## 1. Basic principles

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### Far-Field measurement

- Illuminances measured at a large distance to the light source are directly calculated (approximation) to **luminous intensities**
- **Luminous flux** can be calculated from the luminous intensity distribution or by calculating the integral of the measured illuminances

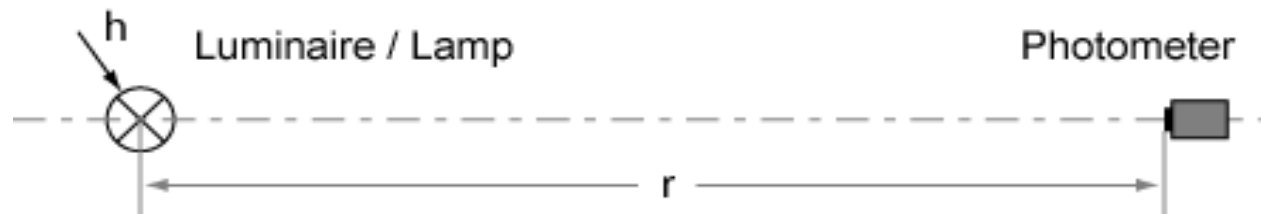
### Near-Field measurement

- Luminance images are captured around the light source by using a **luminance measuring camera**
- The luminance images are transformed to **ray sets** that can easily be calculated to the **luminous intensity distribution (LID)**
- **Luminous flux** can be determined on the basis of the measured luminance images or by calculating the integral of the measured illuminances in case of an available **photometer head** mounted next to the camera



## 2. Principle of far-field goniophometer systems

- Measurement of luminous intensity values using a single illuminance meter at a far field distance to the light source



Error [%]	r/h
0.1	31.6
0.5	14.1
1	<b>9.95</b>
5	4.36
10	3

$$I = E \cdot r^2$$

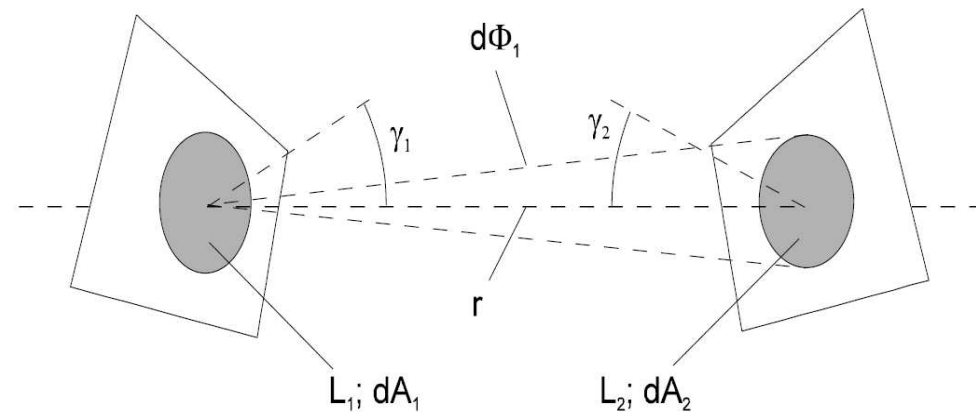
(Lambert radiation!)



## 2.1 Photometric distance law

- Calculation of luminous intensities from illuminances

$$E = \int L(\gamma_1) d\Omega_{p2} \quad [\text{lx}]$$



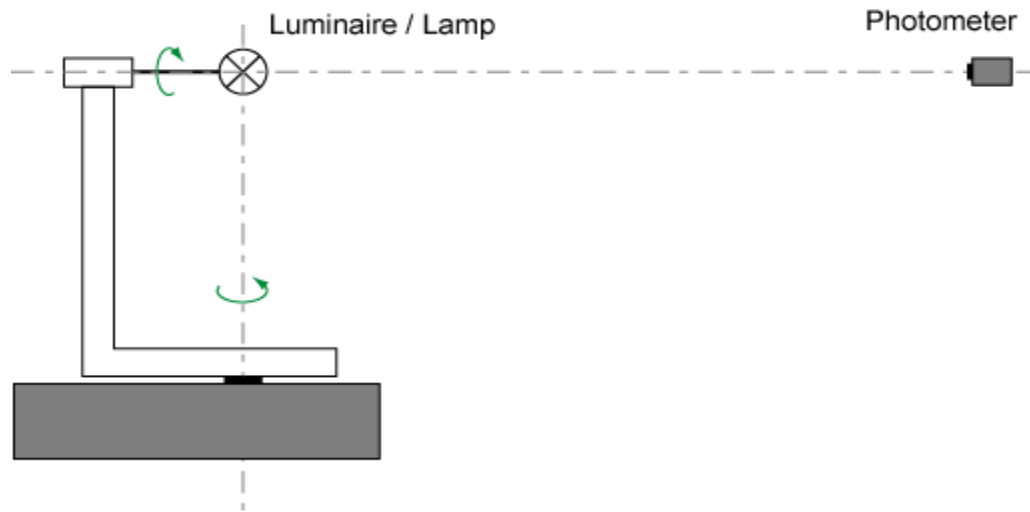
For small solid angles following **approximation** can be done

$$E \approx L(\gamma_1) \Omega_{p2} = \frac{I(\gamma_1)}{r^2} \cos \gamma_2 \Omega_0 \quad \text{Photometric distance law}$$

Small solid angles → Point source → Large distance

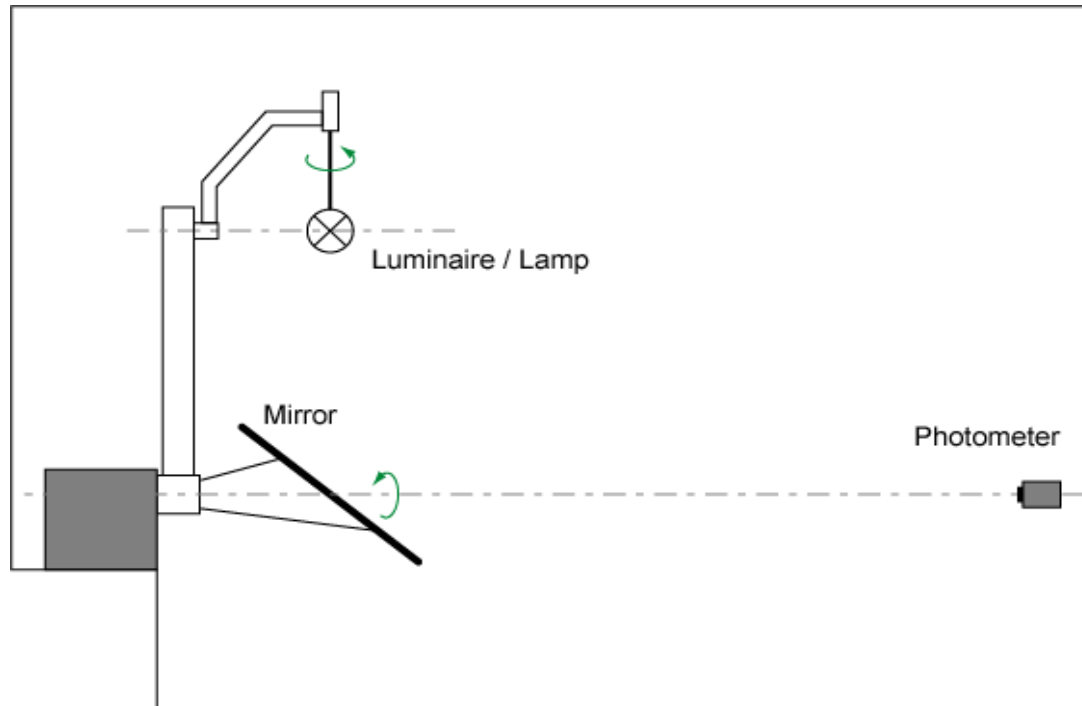


## 2.2 Rotating luminaire goniophotometer





## 2.3 Rotating mirror goniophotometer





## 2.4 Far field goniophometer – advantages / disadvantages

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### Advantages

- + A simple and direct measuring method

### Disadvantages - Rotating luminaire goniophotometer

- Moved luminaire / lamp (→ Instable lamp operation)

### Disadvantages - Rotating mirror goniophotometer

- Large (→ Large laboratory with complex air-conditioning system)
- Expensive
- Sensitive mirror
- Moved luminaire / lamp (up and down -> temperature zones)
- Weak sensitivity for low luminous flux light sources (e.g. single LED)





### 3. Principal of the RiGO801 near-field goniophometers

Idea of Prof. Riemann → **Riemann Goniophotometer**, Patent 1991

**DEUTSCHES PATENTAMT**  
München, den 05.01.94  
Deutsches Patentamt · 80297 München  
Ferndurchwahl: (089) 2195-2705

Aktenzeichen: P 41 10 574.5-52  
Anmeldernr.: 4412559  
RIEMANN U.A.

Patentanwälte  
Dr. Liedtke und Partner  
Postfach 9 56  
99019 Erfurt

INGEGANGEN 12. Jan. 1994

**Erteilungsbeschluss**

Auf die Anmeldung P 41 10 574.5-52 des/der Herrn, Frau, Firma  
Riemann, Manfred, Prof. Dr.sc.techn., 98693 Ilmenau,  
DE; Schmidt, Franz, Dr.sc.techn., 98693 Ilmenau, DE;  
Poschmann, Ralf, Dipl.-Ing., 98693 Ilmenau, DE;  
wird ein vom 31.03.1991 an laufendes Patent  
unter der Bezeichnung  
Verfahren und Anordnung zur Messung der  
Lichtstärkeverteilung von Leuchten und Lampen  
mit den Unterlagen gemäß beigefügter Ablichtung des Vordrucks  
P2480, die Bestandteil dieses Beschlusses ist,  
erteilt.  
Das Patent führt die Nummer 4110574.

Empfangsbescheinigung **110497** DEUTSCHES PATENTAMT

① Sendungen des Deutschen Patentamts sind zu richten an:  
Dr. Pöhner, Dr. Liedtke & Partner  
Patent- und Rechtsanwälte  
Waidmühlenweg 31  
Postfach 956  
99019 Erfurt

**Antrag auf Eintragung eines Gebrauchsmusters**  
Aktenzeichen 297 06 488.6 (vergeben)

② Zeichen des Anmelders/Vertreters (max. 20 Stellen) 1923  
Telefon des Anmelders/Vertreters 0361/2606393  
Datum 03.04.97

③ Der Empfänger in Feld ① ist der  
 Anmelder  Zustellungsbevollmächtigte  Vertreter ggf. Nr. der Allgemeinen Vollmacht

④ **Anmelder** TechnoTeam Bildverarbeitung GmbH  
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**Vertreter**

⑤ Anmeldercode-Nr. 21 40 94  
Vertretercode-Nr.  
Zustelladrecode-Nr.

⑥ **Bezeichnung der Erfindung**  
Anordnung zur Messung der Lichtstärkeverteilung von Leuchten und Lampen

⑦ **Sonstige Anträge**  
 Aussetzung der Eintragung und Bekanntmachung für \_\_\_\_\_ Monate (Max. 15 Monate ab Anmelde- bzw. Prioritätstag)  
 Recherchenantrag - Ermittlung der öffentlichen Druckschriften (§7 Gebrauchsmustergesetz)  
 Lieferung von Ablichtungen der im Recherchenverfahren ermittelten Druckschriften

⑧ **Erklärungen**  
 Teilung/Ausscheidung aus der Gebrauchsmusteranmeldung → G  
Abnahme aus der Gebrauchsmusteranmeldung

s. Kostenhinweise auf der Rückseite

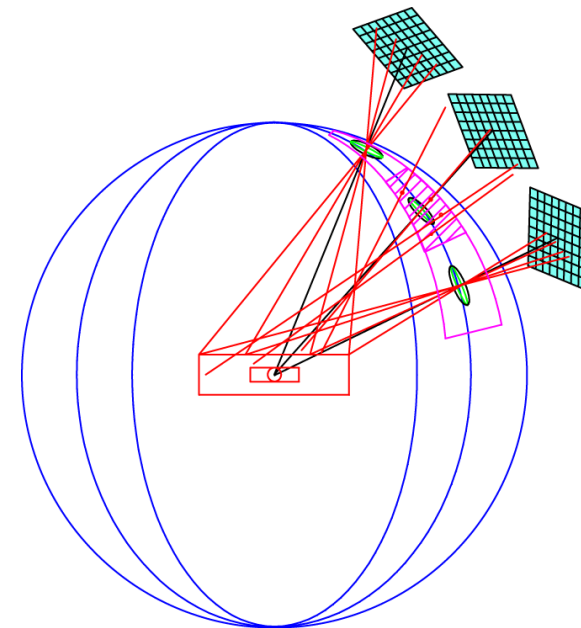
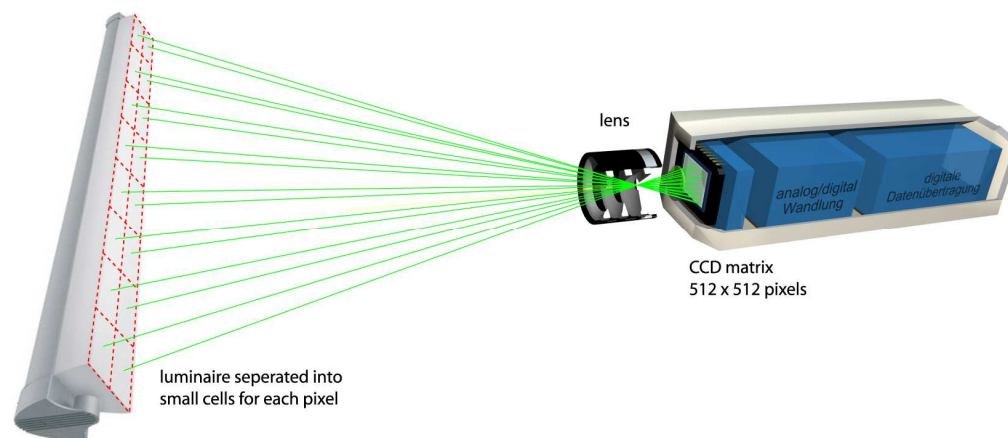
Aktenzeichen  
Anmeldetag



### 3.1 CCD luminance measuring camera

- A Luminance measuring camera (CCD) is moved around the measuring object
- The pixels of the CCD sensor can be regarded as small single sensors (512x512 px)
- The area of each pixel represents a very small solid angle that measured a portion of luminous flux

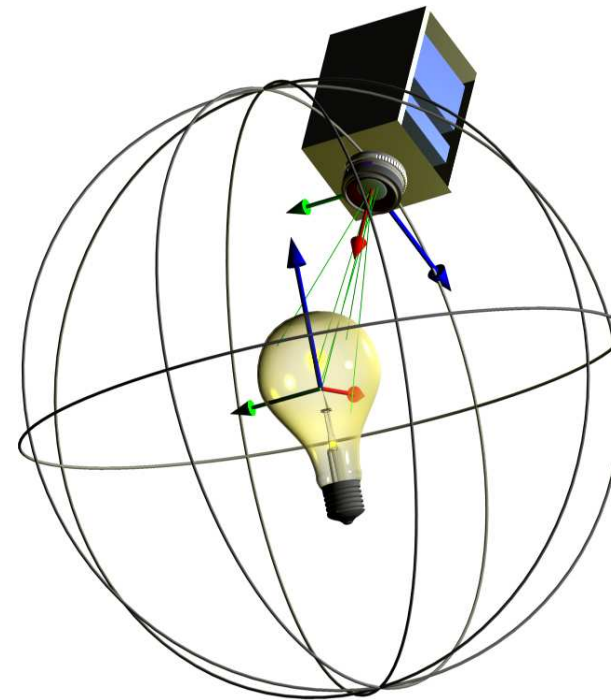
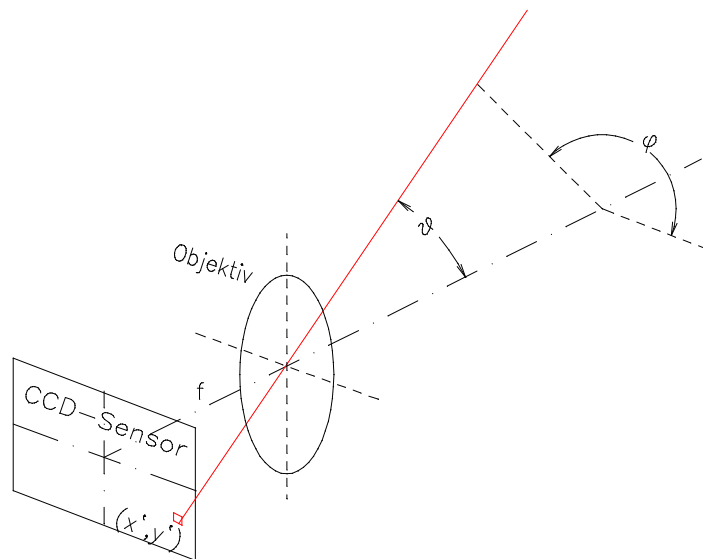
→ **Far field conditions at a close distance**





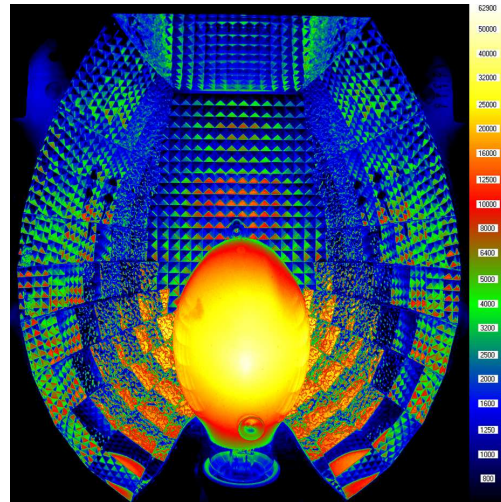
## 3.2 Calculation of ray - directions

- The luminous flux portion measured by a pixel is represented as a vector
- With the exact knowledge of the optical imaging system (lens) the vector direction for each pixel can be calculated precisely





### 3.3 Calculation of ray – amplitudes



The camera measures luminance values of each pixel

$$L(x', y') \quad [\text{cd/m}^2]$$

Weighting with the corresponding solid angles

$$\Delta\Omega(x', y') \quad [\text{sr}]$$

→ **Luminous flux portions**  $\Delta\Phi(x', y') \quad [\text{lm}]$

Calculation of direction and amplitude for each pixel

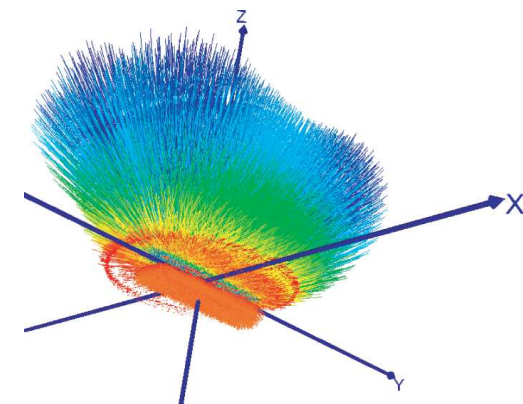
→ Ray bundle for each image

Ray bundles of all images

→ **Complete ray set**

$$\Phi(x, y, z, \vartheta, \varphi)$$

Complete description of light output characteristic

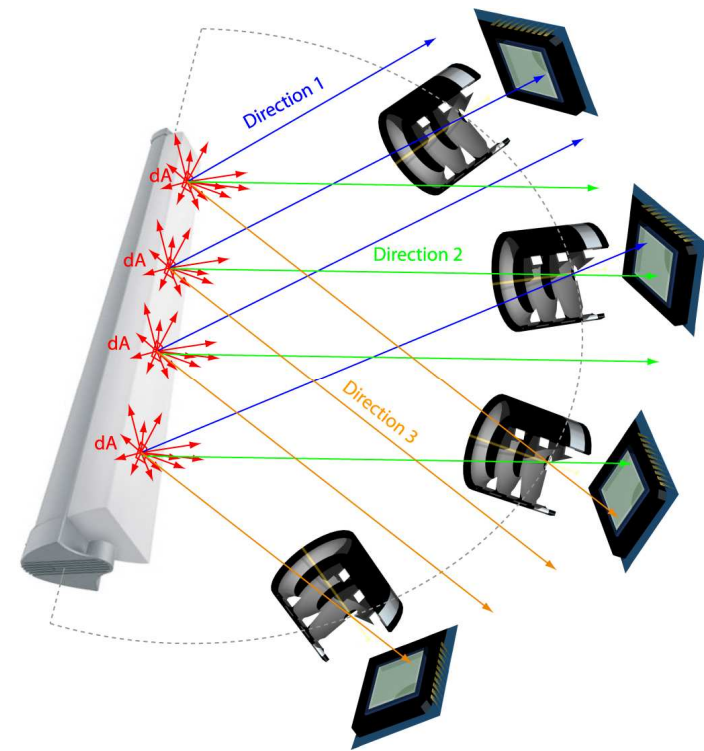
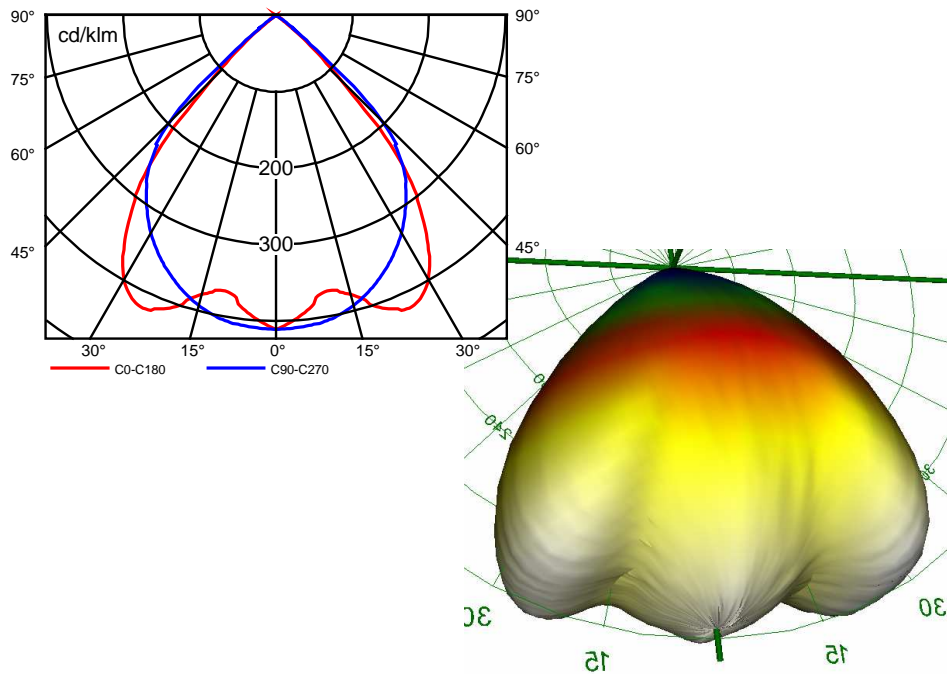




### 3.4 Far-field luminous intensity distribution from ray sets

- All rays are accumulated in direction cells (standard algorithm)  
→ **Luminance intensity distribution**

$$I(\vartheta, \varphi)$$





### 3.5 Luminous flux measurement using the photometer

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- RiGO801 goniophotometers use an **additional illuminance meter**
- Robust method to measure the **luminous flux by integration of illuminance** values on a closed surface around the object

$$\Phi = \int E dA \quad [\text{lm}]$$

- Also Photometer based LID measurements of small objects
- Simple calibration procedure by measuring a luminous flux standard lamp





### 3.6 Advantages of RiGO 801

- Relative small and lightweight construction  
→ No extra large laboratories required
  - Measuring object is not moved  
→ Stable conditions of light output
  - Hanging and upstanding support  
→ Easy measurement of direct indirect luminaires
  - Fast measurements  
→ e.g. 25 minutes for 2.5° x 2.5°)
  - High resolution  
→ Up to 0.1° x 0.1° possible
  - Easy alignment of the light source by using the camera
  - Position independent measurement by principle  
→ No need to consider the light centroid
  - Luminance measuring camera  
Luminance images can be used for different tasks
- Cost-efficient regarding to conventional goniophotometers





### 3.7 RiGO801 and the standards

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- DIN 5032-1, Part 1: Photometrical methods  
→ The type of movement (movement on a virtual spherical surface) is mentioned
  - DIN EN 13032-1 (Partial replacement of DIN 5032-1)  
→ Measurement of luminous intensity by integrating luminances mentioned
  - Work in the technical committee FNL-3 (DIN), Dr. Schmidt  
→ Luminance measurement and near field goniophotometer
  - Work in CIE committee (TC2-62), Dr. Krueger  
→ Technical recommendation which includes the near-field goniophotometers
- RiGO801 technique established at several large luminaire and lamp manufacturers





## 3.8 References

- Ansorg GmbH Lichttechnik, DE <sup>1</sup>
- Audi AG, DE <sup>3</sup>
- AE Schreder GmbH, AT <sup>1</sup>
- D. Swarovski & Co. Lichtlabor, AT <sup>1</sup>
- Diehl Aerospace GmbH, DE <sup>3</sup>
- Fraunhofer Institut Solare Energiesysteme, DE <sup>4</sup>
- Fraunhofer Institute for Reliability and Microintegration, DE <sup>3</sup>
- FH Ravensburg/Weingarten, DE <sup>2</sup>
- Goodrich Lighting Systems, DE <sup>1</sup>
- Heraeus Noblelight GmbH, DE <sup>4</sup>
- Ilexa GmbH, DE <sup>3</sup>
- KaHo Sint-Lieven, BE <sup>1 2 3</sup>
- Karlsruher Institut für Technologie, LTI, DE <sup>2</sup>
- KPU, Korea Polytechnic University, Seoul, KR <sup>2</sup>
- Lehner Werkmetall GmbH, DE <sup>1</sup>
- LICHT Design Management, DE <sup>1</sup>
- L-Lab, DE <sup>3</sup>
- Magistrat der Stadt Wien, MA 39, AT <sup>1</sup>
- OMS Ltd., Slovakia <sup>1</sup>
- OSRAM GmbH, Herbrechtingen, DE <sup>2</sup>
- OSRAM GmbH, Munic, DE <sup>2</sup>
- Philips Technologie GmbH, DE <sup>2</sup>
- Regent Beleuchtungskörper AG, Switzerland <sup>1</sup>
- Riegens A/S, Denmark <sup>1</sup>
- RZB Leuchten, DE <sup>1</sup>
- SGS Fimko Ltd, Finland <sup>1</sup>
- SITECO, DE <sup>1</sup>
- Sony Corporation, Tokyo <sup>3</sup>
- Spittler Lichttechnik GmbH, DE <sup>1</sup>
- Technische Universität Berlin, DE <sup>3</sup>
- Technische Universität Ilmenau, DE <sup>1 2</sup>
- TRILUX GmbH & Co. KG, DE <sup>1</sup>
- TULUX AG, Switzerland <sup>1</sup>
- University of Tehran <sup>1</sup>
- VNISI, Russian Lighting Research Institute, Moscow <sup>1</sup>
- Zumtobel STAFF GmbH & Co. KG, DE <sup>10</sup>

<sup>1</sup> RiGO801 – Luminaire   <sup>2</sup> RiGO801 – Lamps   <sup>3</sup> RiGO801 – LED   <sup>4</sup> Special